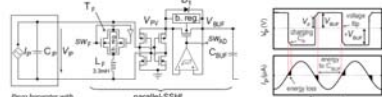


## Introduction

Tyndall has a research trajectory in MEMS scale AlN Piezo transducers. There are numerous and quite disparate techniques for maximising power extraction from AC piezoelectric sources – AC MPPT. This work involves experimental characterisation and modelling of a high frequency (stiff) AlN on Silicon prototype transducer to create and validate dynamic electro-mechanical models for use in AC front end design in Mischief II. The key question is around the magnitude of the reverse piezo effect and how much adverse electrical damping will be created by the HF resonant bias flip, versus the gained increased rectifier conduction angle.

Piezo – Energy Extraction at Mechanical Vibration Frequency from a Capacitive Source

- At the vibration frequency ( $\omega_0$ ) – facilitates ULP
- A quickly evolving variety of Active Rectifier, Conduction Angle Extension (Bias Flip, Parallel Synchronous Switch Harvesting on Inductor (P-SSH)) or other Synchronous Charge Extraction (SECE) techniques.



\*As built for Cork Parallel SSH Rectifier for Piezoelectric Energy Harvesting of Periodic and Shock Excitations with Inductor Shaping, Gold Start-up and up to 500 W Power (Enterprise Implementation), Daniel A. Sanchez et al., 2010-2018

## Device structure

- The piezoelectric material (AlN) is sandwiched between two metal thin films, as shown.
- The piezoelectric material dispenses positive and negative ions when external force is applied – adaptive energy harvester.
- 50um Si thickness (Dry Reactive Ion Etch)
- Piezoelectric material (AlN) a 5mm\*2mm
- Device 5mmX8mm



Figure 1 : Actual device

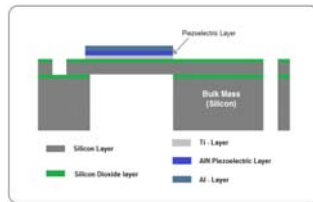


Figure 2 : Device layer structure

## COMSOL and Electrical Model

- The model is flexible, meaning device geometries can be designed to compare the results of devices with different parameters.

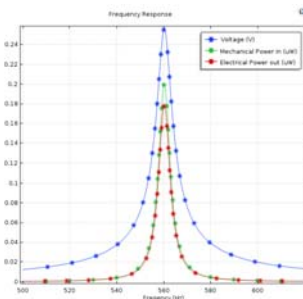


Figure 3: COMSOL Model output graph

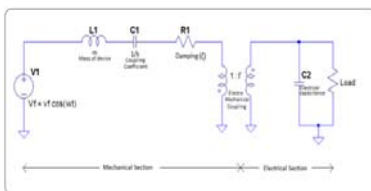


Figure 4: Electro-Mechanical Model

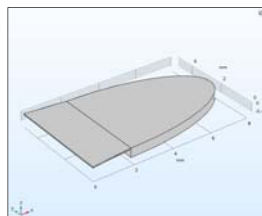


Figure 5: COMSOL Model

## Experiment using the Electromechanical Shaker

- The shaker provides constant controlled vibration source with specific acceleration.
- For acceleration of 0.1g, the device generates 170 nW with load of 550 kΩ and resonance at 545 Hz.
- Mechanical displacements are determined by replication of generated voltages with loudspeaker system mounted under laser vibrometer (+/- 175um)

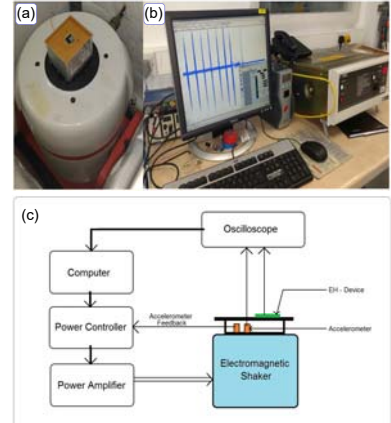


Figure 6: (a) VTS V455/6-PA1000L Shaker, (b) Experimental setup and (c) Block diagram of setup

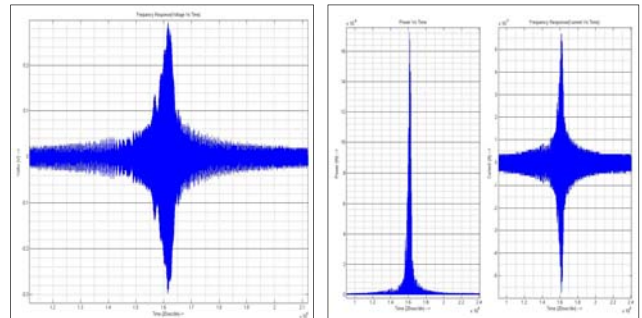


Figure 7: Experiment results using Electromagnetic Shaker

## Future work

- Narrow bandwidth – implies constrained resonant frequency tuned applications and custom mechanical design per application
- Optimisation of piezoelectric and electrode materials required – enhanced power harvesting.
- Determination of practical power transductions in broadband and shock induced vibrational applications
- Further validation of key parameters such as mechanical damping coefficient and piezo constitutive forward and reverse coupling factor
- Design of low drop-out Active Rectifier for ULP and low voltage AC source in 180nm SOI
- Determination of power transfer increase with Bias Flip and SECE methods